

Polymer evaporation system

Specifications:

- **WAFER SIZE:** 2" wafer can be used.
- **Material DEPOSITED:** Polymer-Pentacene
- **SUBSTRATE TEMPERATURE:** Room temperature to 70°C.
- **GASES USED IN THE SYSTEM:** Nitrogen for venting.
- **BASE PRESSURE:** 4×10^{-6} mbar.

Process Capabilities:

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